

Catalog # 93-1387 Aluminum chloride, anhydrous, reagent, 99%

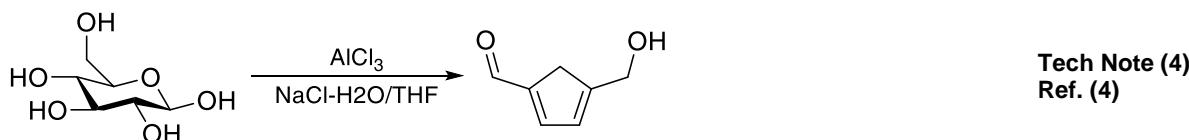
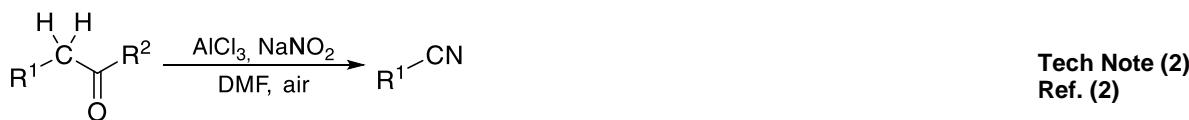
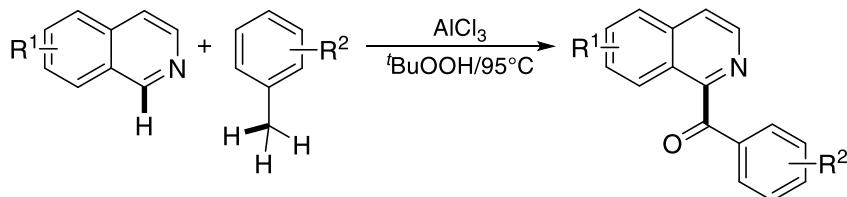
AlCl₃

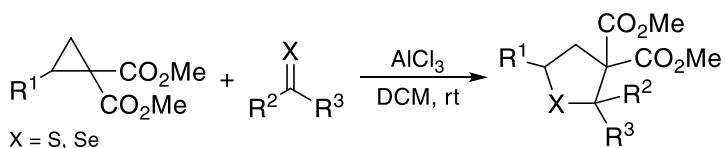
Catalysis Applications

AlCl₃ is a typical Lewis-acid catalyst for used in organic synthesis

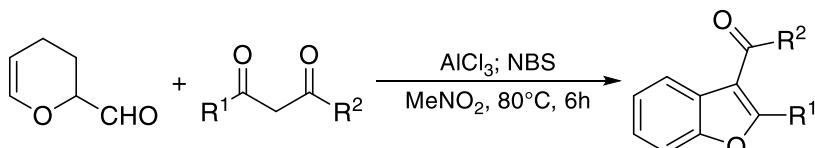
Technical Notes:

1. Catalyst for regiospecific benzoylation of electron-deficient *N*-heterocycles with Methylbenzenes via a Minisci-type reaction
2. Used in transition-metal-free deacylative cleavage of unstrained C(sp³)–C(sp²) Bonds to generate aryl and aliphatic nitriles from ketones and aldehydes
3. Catalyst for microwave-assisted alcoholysis of furfural alcohol into alkyl levulinates
4. Catalyst for the transition metal- and cyanide-free one-step direct transformation of methylarenes into pharmaceutical-oriented aryl nitriles
5. Catalyst for the conversion of glucose to 5-hydroxymethylfurfural (HMF) in NaCl-H₂O/THF
6. Used in Lewis-acid-catalyzed reactions of 2-substituted cyclopropane 1,1-dicarboxylates with thioketones
7. Catalyst used for the synthesis of benzofurans and 4,5,6,7-tetrahydrobenzofurans from acrolein dimer and 1,3-dicarbonyls
8. Catalyst used in ring-opening reactions of donor-acceptor cyclobutanes with electron-rich arenes, thiols, and selenols
9. Catalyst for the synthesis of highly substituted phenols and benzenes with complete regiochemical control
10. Catalyst for the C-H phosphination of benzene

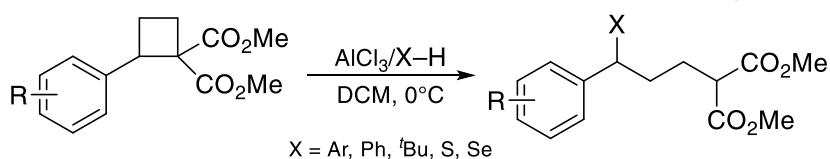




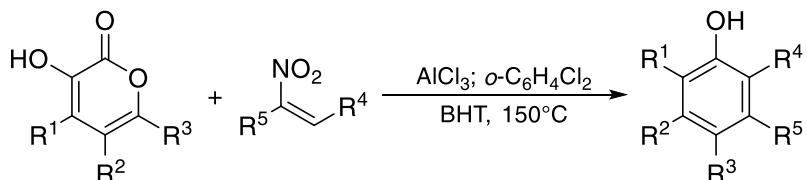
Tech Note (5)
Ref. (5)



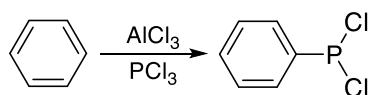
Tech Note (6)
Ref. (6)



Tech Note (7)
Ref. (7)



Tech Note (8)
Ref. (8)



Tech Note (9)
Ref. (9)

References:

1. [J. Org. Chem. 2015, 80, 5625.](#)
2. [Org. Lett. 2016, 18, 228.](#)
3. [J. Am. Chem. Soc. 2016, 138, 3294.](#)
4. [ACS Catal. 2017, 7, 256.](#)
5. [Angew. Chem. Int. Ed. 2017, 56, 14293.](#)
6. [J. Org. Chem. 2019, 84, 2941.](#)
7. [Org. Lett. 2019, 21, 6315.](#)
8. [Org. Lett. 2020, 22, 6086.](#)
9. [Appl. Catal. A, 2021, 611, 117943.](#)

CVD/ALD Applications

Thermal Behavior:

- Sublimation at 180°C
- Decomposition at 262°C

Technical Notes:

1. ALD precursor used for Al thin film deposition

| Target Deposit | Deposition Technique | Delivery Temperature | Pressure | Co-reactants | Deposition Temperature | Ref. |
|--|----------------------|----------------------|-----------|--|------------------------|------|
| Al | ALD | 95°C | - | AlH ₂ (tBuN)(CH ₂) ₂ (NMe ₂) | 140°C | 1 |
| Al ₂ O ₃ | ALD | - | 0.75 Torr | Al(OEt) ₃ | 400°C | 2 |
| | ALD | 80°C | 0.75 Torr | Al(O'Pr) ₃ | 150-375°C | 3 |
| | ALD | - | - | H ₂ O | 300-800°C | 4 |
| | ALD | - | 0.75 Torr | | 250-300°C | 5 |
| | ALD | 100°C | 0.5 Torr | H ₂ O | 200°C | 6 |
| | ALD | 100°C | - | O ₃ | 300-450°C | 7 |
| Nb ₂ O ₅ :Al ₂ O ₃ | ALD | 99°C | 0.75 Torr | Nb(OEt) ₅ , H ₂ O | 300°C | 8 |
| TiO ₂ :Al ₂ O ₃ | ALD | 70°C | 0.75 Torr | TiCl ₄ , H ₂ O | 80-250°C | 9 |
| AlN | ALD | 140°C | 0.6 Torr | NH ₃ | 500-550°C | 10 |

References:

1. [*Chem. Mater.* **2018**, 30, 1844](#)
2. [*Science* **2000**, 288, 319](#)
3. [*J. Mater. Chem.* **2002**, 12, 1415](#)
4. [*J. Appl. Phys.* **2006**, 99, 054902](#)
5. [*J. Phys. Chem. C* **2008**, 112, 15791](#)
6. [*Chem. Mater.* **2021**, 33, 3926](#)
7. [*Thin Solid Films* **2014**, 565, 19](#)
8. [*J. Electrochem. Soc.* **2001**, 148, F35](#)
9. [*Eur. Pol. J.* **2008**, 44, 3564](#)
10. [*J. Vac. Sci. Technol. A* **2019**, 37, 020925](#)